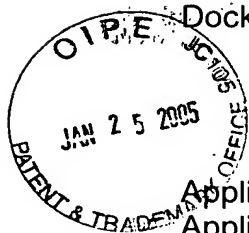


Docket No.: L&L-I0242



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 10/694,593
Applicant : Olaf Storbeck, et al.
Filed : October 27, 2003
Art Unit : 2811
Title : Method for Minimizing the Vapor Deposition of Tungsten-Oxide
During the Selective Side Wall Oxidation of Tungsten-Silicon
Gates
Docket No. : L&L-I0242
Customer No. : 24131

STATUS LETTER

Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450

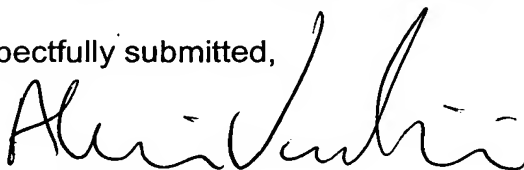
Sir:

It is respectfully requested that this Status Letter be returned to:

LERNER AND GREENBERG, P.A.
Post Office Box 2480
Hollywood, FL 33022-2480
Tel: (954) 925-1100
Fax: (954) 925-1101

with an indication as to when an action may be expected.

Respectfully submitted,


Alexia J. Vrahimis

Date: January 21, 2005

/av